Linear Stage - LS65x.Lab Series

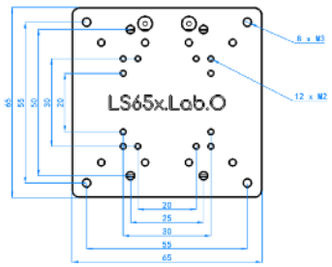
High-load horizontal motion units with high resolution

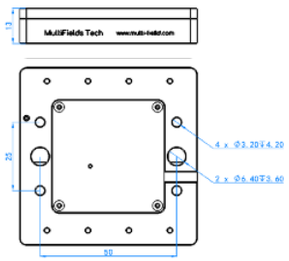
LS65x.Lab.O.NM /.HV /.UHV

Features

- Very Quiet, 20 kHz drive frequency
- Compact Design, 65 mm × 65 mm × 13 mm
- Closed-loop control, Resistive Position Sensor (.R) or Optic Encoder (.O)
- High Precision -Resolution (.O): 4.88 nm,2.44 nm or 10 nm, 1nm optional
- Economy type -Resolution (.R): 100 - 200nm
- Mini Step Size, ~ 10 nm
- Multi-axis stacking adapters available
- Controller compatible with rotary and tilting stage
- Support Options, non-magnetic (.NM)、high vacuum (.HV) & ultra- high vacuum (.UHV)

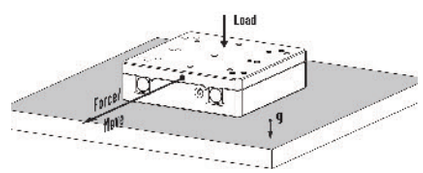
2D·Drawings



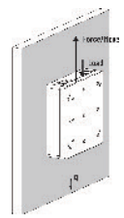


LS65x.Lab.O/.R - Specification

	Optional Versions ⇨	Standard	.NM	.HV	.UHV
		.NM, non-magnetic; .HV, high vacuum compatible; .UHV, ultra-high vacuum compatible;			
1	Dimension	65 × 65 mm × 13 mm			
2	Main Material	Aluminium/ Stainless	Aluminium/ Pure Ti	Aluminium/ Stainless	Aluminium/ Stainless
3	Mass	332 g	204 g	332 g	332 g
4	Cable & Connectors	Standard shielded cable circular connector and D-Sub15		kapton shielded wire, 2mm PEEK pins	
Motion parameters for recommended installation I					
5	Travel Range	30 mm			
6	Velocity	~ 20 mm/s (max)*			
7	Mini Step Size	~ 10 nm			
8	Drive Frequency	Max. 20 kHz (very quiet)			
9	Dynamic Force	2 N (max)			
10	Holding Force	5 N			
11	Pitch / Yaw	0.3 mrad (0.017°)			
12	Load	2 kg (max)			
Motion parameters for recommended installation II					
13	Load	150 g (max)			
14	Holding Force	5 N			
Sensor					
15	Sensor Type	- Resistive Sensor (.R) - Optic Encoder (.O)			
16	Sensor Range	30 mm			
17	Sensor Resolution	-Resistive Sensor (.R), 100 - 200 nm -Optic Encoder (.O), 10 nm or 4.88 nm,2.44 nm, 1nm optional (default-10nm)			



Installation I



Installation II

Piezoelectric Motion - RT

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